

# Evactron® 40



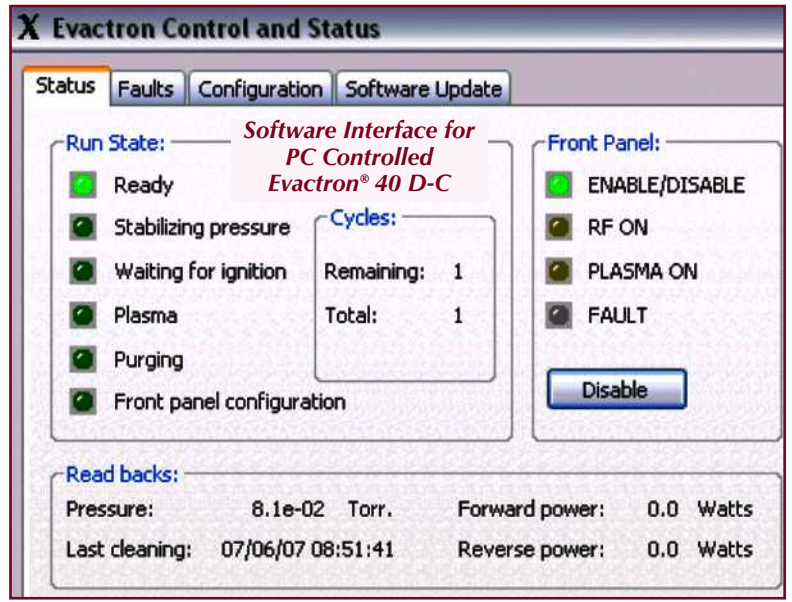
## NEW! Evactron 40 De-Contaminator

**X**EI SCIENTIFIC introduces our exciting new Evactron® 40 De-Contaminator (D-C) for cleaning scanning electron microscopes. We're pushing the frontiers electron microscope cleaning technology to improve resolution and imaging time for 21st century needs.

Evactron® D-C cleaning uses a unique, cutting edge process for remote plasma production of oxygen radicals that flow downstream through your system, removing hydrocarbons.

These new user friendly Evactron® D-C models optimize remote plasma cleaning perfectly to the needs of the user.

*Gentle. Fast. Convenient and Effective Cleaning*

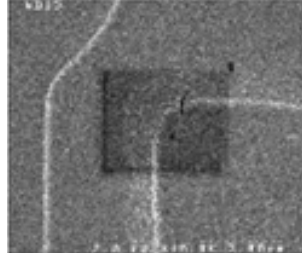


- Comes with Graphical User Interface
- Automatically set pressure and power settings of the plasma
- Increased cleaning efficiency by running multiple plasma and purge cleaning conditions and cycles
- Cleaning and error logs record cleaning history and aids trouble shooting
- Electronic Chassis: H 3.5" x W 19.5" x D 7"
- RF Power: 5 - 20 Watts at 13.566 MHz
- KF 40 vacuum mounting flange
- 100-240 VAC 50/60 Hz input
- Evactron® 40 D-C is a PC Controlled version that works the same way as the Evactron® 45

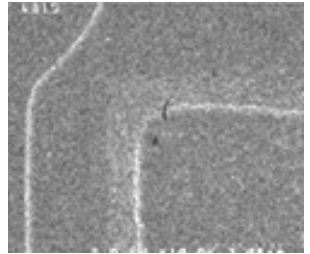
Try the Evactron® Process in your lab, free, [shipping charges apply] for 30 days by placing an evaluation PO by January 15, 2008.



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Unwanted Artifact



After Evactron® Cleaning